

Form PTO-1449 (modified)

Atty. Docket No.

102-0075US2

Serial No.

10/762,706

List of Patents and Publications for Applicant's

Applicant / Inventor

Micron Technology, Inc., / Cem Basceri et al.

INFORMATION DISCLOSURE STATEMENT

Filing Date:

1/22/2004

Group:

unk

(Use several sheets if necessary)



U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
<i>1/22</i>	A1	6080446	6/27/2000	Tobe et al.	427	255.394	
<i>1/22</i>	A2	6596085	7/22/2003	Schmitt et al.	118	726	2/1/2000
<i>1/22</i>	A3	5380396	1/10/1995	Shikida et al	156	630	
<i>1/22</i>	A4	6705345	3/16/2004	Bifano	137	597	11/8/2000
<i>1/22</i>	A5	6432831	8/13/2002	Dhindsa	438	710	3/23/2001
<i>1/22</i>	A6	6358323	3/19/2002	Schmitt et al.	118	726	6/21/1998
<i>1/22</i>	A7	6302964	10/16/2001	Umotoy	118	715	3/16/2000
<i>1/22</i>	A8	6287980	9/11/2001	Hanazaki et al.	438	726	10/12/1999
<i>1/22</i>	A9	6245192	6/12/2001	Dhindsa et al.	156	345	
<i>1/22</i>	A10	6086677	7/11/2000	Umotoy et al.	118	715	
<i>1/22</i>	A11	6032923	3/7/2000	Biegelsen et al.	251	129.01	
<i>1/22</i>	A12	5953634	9/14/1999	Kajita et al.	438	687	
<i>1/22</i>	A13	5500256	3/19/1996	Watabe	427	579	
<i>1/22</i>	A14	5091207	2/25/1992	Tanaka	427	8	
	A15						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
<i>1/22</i>	B1	2002-164336	6/7/2002	Japan			yes
	B2						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
	C1	

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1763

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
AK	A1	5082517	01-1992	Moslehi	156	345.26	
AK	A2	6176930	01-2001	Koai et al.	118	715	
AK	A3	6548112	04-2003	Hillman et al.	427	248.1	11/18/1999
AK	A4	5911834	06-1999	Fairbairn et al.	134	1.3	
AK	A5	5876503	03-1999	Roeder et al.	118	715	
AK	A6	4934401	06-1990	Ikehata et al.	137	82	
	A7						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
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INFORMATION DISCLOSURE STATEMENT — PTO-1449 (MODIFIED)

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1/22/04

Form PTO-1449 (modified)		Atty. Docket No. 102-0075US-2	Serial No. unknown
List of Patents and Publications for Applicant's INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		Applicant Cem Basceri; Gurtej S. Sandhu	
		Filing Date: August 29, 2002	Group: unknown
U.S. Patent Documents See Page Error! Bookmark not defined.	Foreign Patent Documents See Page 1	Other Art See Page 1	

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
112	A1	4966646	10/30/1990	Zdeblick	156	633	
112	A2	5865417	02/02/1999	Harris et al.	251	11	
112	A3	6062256	05/16/2000	Miller et al.	137	487.5	
112	A4	6123107	09/26/2000	Selser et al.	137	884	
112	A5	6129331	10/10/2000	Henning et al.	251	11	
112	A6	6149123	11/21/2000	Harris et al.	251	11	
112	A7	6160243	12/12/2000	Cozad	219	439	
112	A8	6182603	02/06/2001	Shang et al.	118	723 ME	
112	A9	6210754	04/03/2001	Lu et al.	427	248.1	
112	A10	6237394	05/29/2001	Harris et al.	73	1.88	
112	A11	6290491	09/18/2001	Shahvandi et al.	432	5	
	A12	09/651037		Mardian			08/30/2000
	A13						
	A14						
	A15						
	A16						
	A17						
	A18						
	A19						
	A20						

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U.S. Patent Documents <i>See Page Error! Bookmark not defined.</i>	Foreign Patent Documents <i>See Page 2</i>	Other Art <i>See Page 2</i>	

Foreign Patent Documents

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	B1						
	B2						
	B3						
	B4						
	B5						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
1/22	C1	A.K. Henning et al, "Microfluidic MEMS for Semiconductor Processing," IEEE Transactions on Components, Packaging, and Manufacturing Technology B21, pp. 329-37 (1998)
1/22	C2	A.K. Henning, "Microfluidic MEMS," Proceedings: IEEE Aerospace Conference, Paper 4.906 (IEEE Press, Piscataway, NJ, 1998)
1/22	C3	J.S. Fitch et al., "Pressure-Based Mass-Flow Control Using Thermopneumatically-Actuated Microvalves," Proceedings: Solid-State Sensor and Actuator Workshop, pp. 162-65 (Transducers Research Foundation, Cleveland, OH, 1998)
1/22	C4	A.K. Henning et al., "Contamination Reduction Using MEMS-Based, High-Precision Mass Flow Controllers," Proceedings: SEMICON West Symposium on Contamination Free Manufacturing for Semiconductor Processing (SEMI, Mountain View, CA, 1998)
1/22	C5	A.K. Henning, "Liquid and Gas-Liquid Phase Behavior in Thermopneumatically Actuated Microvalves," Proceedings: Micro Fluidic Devices and Systems, Vol. 3515, pp. 53-63 (International Society for Optical Engineering, Bellingham, WA, 1998)
1/22	C6	A.K. Henning et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings: Micromachined Devices and Components, Vol. 3514, pp. 159-170 (International Society for Optical Engineering, Bellingham, WA, 1998)

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Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
AK	C7	A.K. Henning et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings: SEMICON West Workshop on Gas Distribution (SEMI, Mountain View, CA, 1998)
AK	C8	D. Maillefer et al., "A High-Performance Silicon Micropump for Disposable Drug Delivery Systems," Proceedings of the MEMS 2001 Conference, Interlaken Switzerland, pp. 413-17 (2001)
AK	C9	R. Bardell et al., "Designing High-Performance Micro-Pumps Based On No-Moving-Parts Valves," ASME— Microelectromechanical Systems (MEMS), DSC-Vol. 62 HTD-Vol. 354, pp. 47-53 (1997)
AK	C10	A. Olsson, "Valve-Less Diffuser Micropumps" (1998), published at http://www.s3.kth.se/mst/research/dissertations/pdf/andersodoc.pdf .
AK	C11	Redwood MicroSystems Introduces Semiconductor Grade Products, 07/12/00, published at www.redwoodmicro.com/semicon.html , pages 1 and 2.
AK	C12	P. Woias, "Micropumps—Summarizing the First Two Decades," Proceedings: SPIE— International Society for Optical Engineering, Vol. 4560, pp. 39-52 (2001)
AK	C13	A.K. Henning et al., "A Thermopneumatically Actuated Microvalve for Liquid Expansion and Proportional Control," Proceedings: Transducers '97: 1997 International Solid State Sensors and Actuators Conference, pp. 825-28 (IEEE Press, Piscataway, NJ, 1997)
AK	C14	U.S. Patent Application filed August 23, 2002, inventors Cem Basceri & Gurtej Sandhu, entitled "Reactors Having Gas Distributors and Methods for Depositing Materials Onto Micro-device Workpieces" (Micron Docket 01-1047; U.S. patent application serial number not yet assigned).

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